

3D TECHNOLOGIES: SOME PERSPECTIVES FOR MEMORY INTERCONNECT AND CONTROLLER

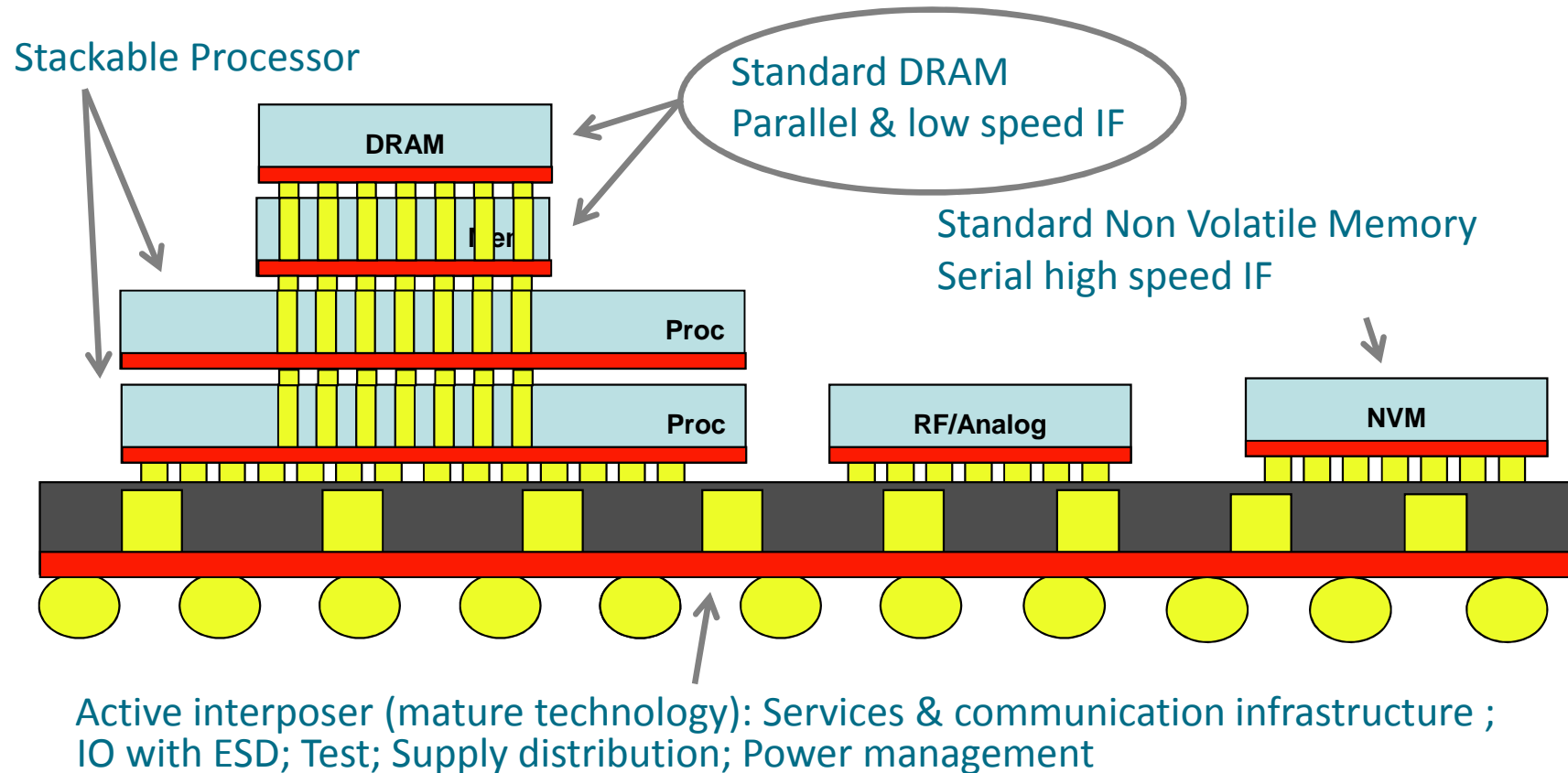
CODES+ISSS: Special session on memory controllers

Taipei, October 10th 2011

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3D-IC design: will dream become reality ?

- Example of an heterogeneous 3D-IC stack:



- This presentation focuses on vertical interconnect between complex MPSoC and memory

Outline

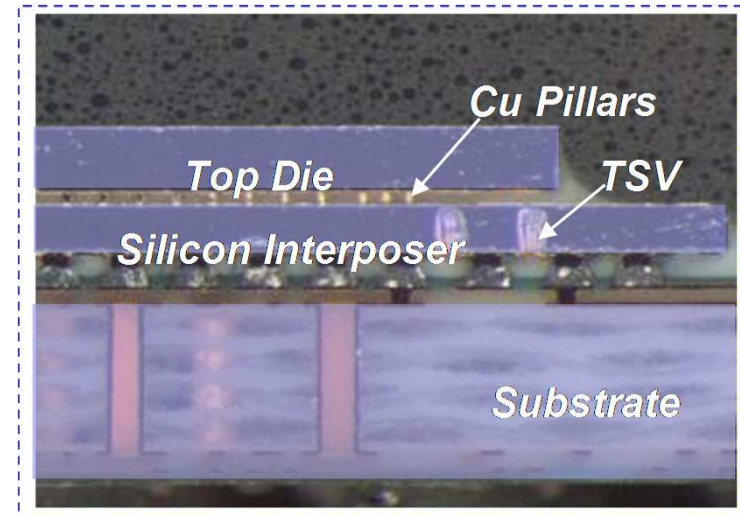
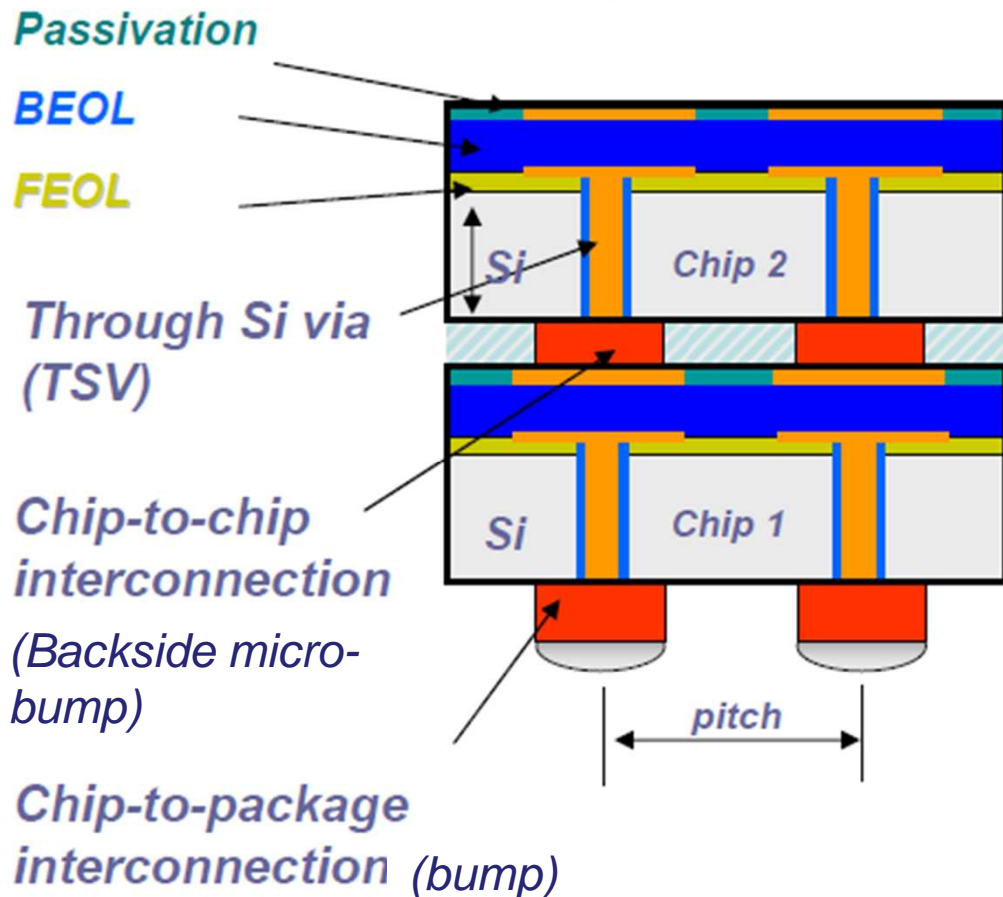
- Introduction
- 3D TSV technology choices
 - 3D-IC toolbox
 - Design perspectives
- Improving memory bandwidth
 - The memory link bottleneck
 - Overview of memory interfaces: bandwidth, power consumption, package integration
- Wide IO interface integration: Mag3D circuit
 - Wide IO technology
 - Mag3D circuit: architecture, Wide IO DRAM integration, design implementation challenges and current results
- Conclusion & perspectives

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3D IC: Some definitions

- 3D-IC chip stacking: Adding a new vertical interconnect chain in CMOS : Through Silicon Via + backside bump

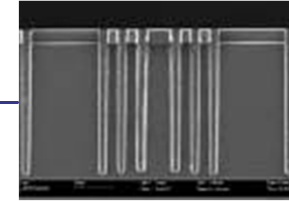
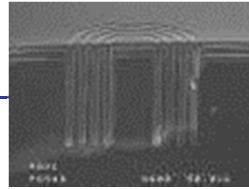


BEOL: Back-End-Of-Line
FEOL: Front-End-Of-Line

3D IC interconnect: Through Silicon Via

Via First TSV (Polysilicon filled)

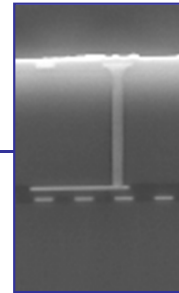
Processed before CMOS front-end steps
Pitch: $\sim 10\mu\text{m}$
Density: 10000 TSV/ mm^2



Trench AR 20,
 $5 \times 100\mu\text{m}$

Via Middle TSV (Copper filled)

Processed after CMOS front-end steps
Pitch: $40\mu\text{m}$ to $50\mu\text{m}$
Density: 500 TSV/ mm^2



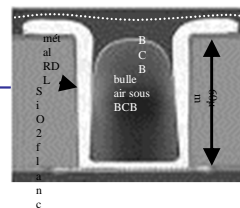
AR 7, $2 \times 15\mu\text{m}$



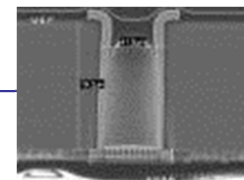
AR 10,
 $10 \times 100\mu\text{m}$

Via Last TSV (Copper liner)

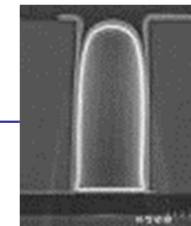
Processed after metallization
Pitch: $\sim 100\mu\text{m}$
Density: 100 TSV/ mm^2



AR 1
 $80 \times 80\mu\text{m}$

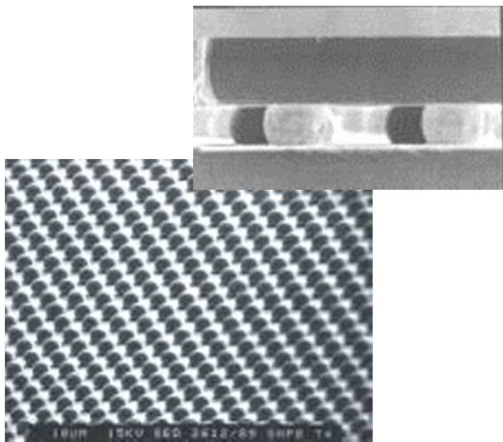


AR 2,
 $60 \times 120\mu\text{m}$

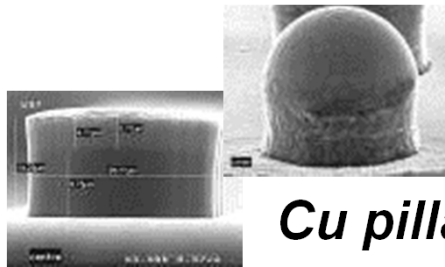


AR 3,
 $40 \times 120\mu\text{m}$

3D IC interconnect: inter-chip connections

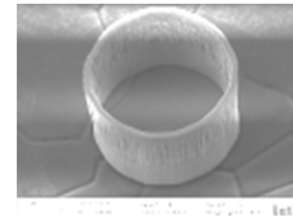


**Classic Flip chip
(Ball or stud bump)**



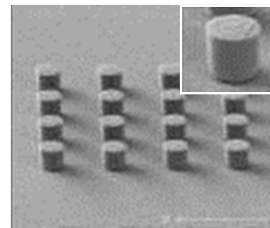
Cu pillars

SnAg Solder



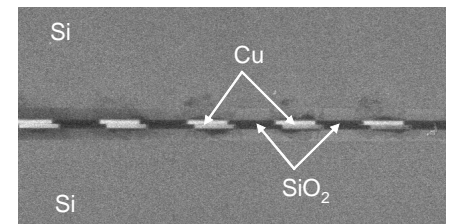
μ tubes

Microinsertion



Solder-free μ inserts

Nickel Microinsertion



Cu-Cu Direct bonding

Need very flat surface
Cleaning

> 100 μ m

100-30 μ m range

30-10 μ m range

Down to 5 μ m

TSV last

TSV middle

TSV first

Pitch

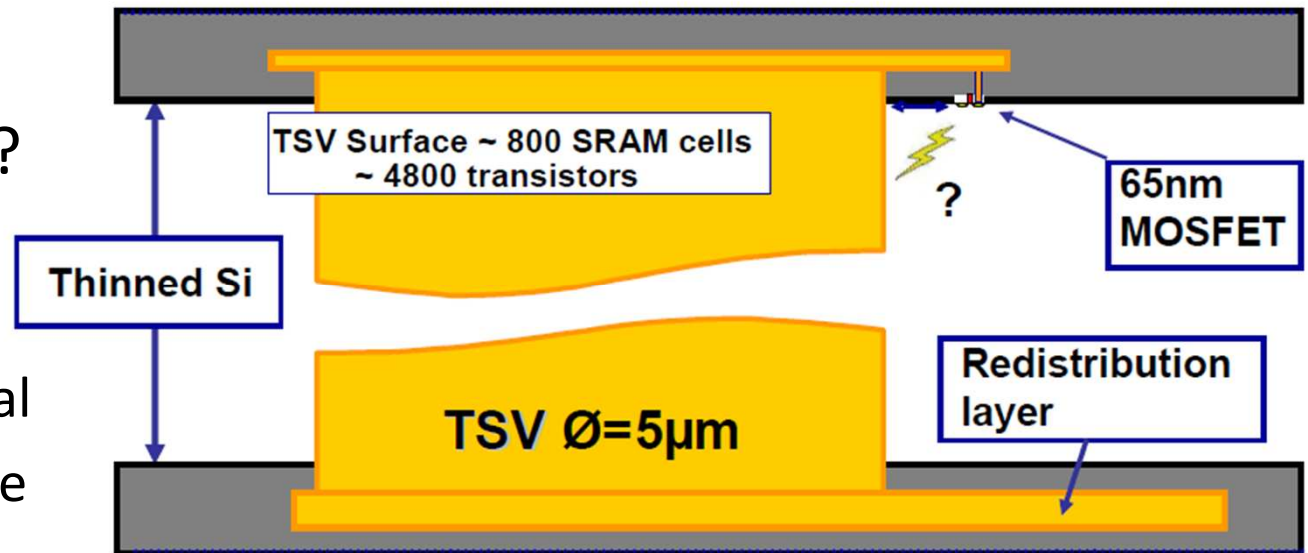
Current TSV technology and design perspectives

1. What can we expect ?

- 10 μm diameter TSV is challenging
- Must add guard interval
- Die thickness is an issue

2. 3D design is not yet mature:

- No accurate CAD tools & models for 3D (CTS, extraction, Thermal, Power ...)
- No accurate test model for TSV



Resulting 3D partitioning ?

- Fine grain partitioning of an operator in two dies using TSV is not a good option
- ⇒ **Coarse grain to medium grain partitioning**

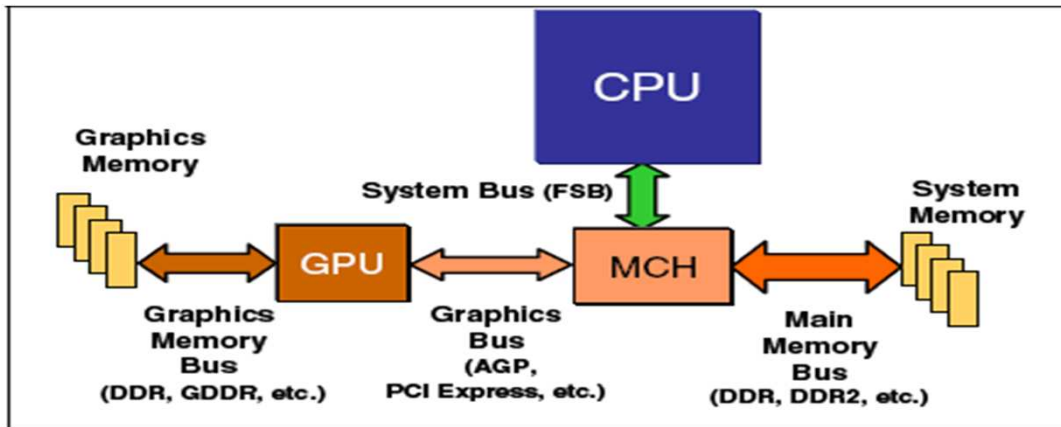
⇒ **Proposal ? 3D Memory (Wide IO)**

Outline

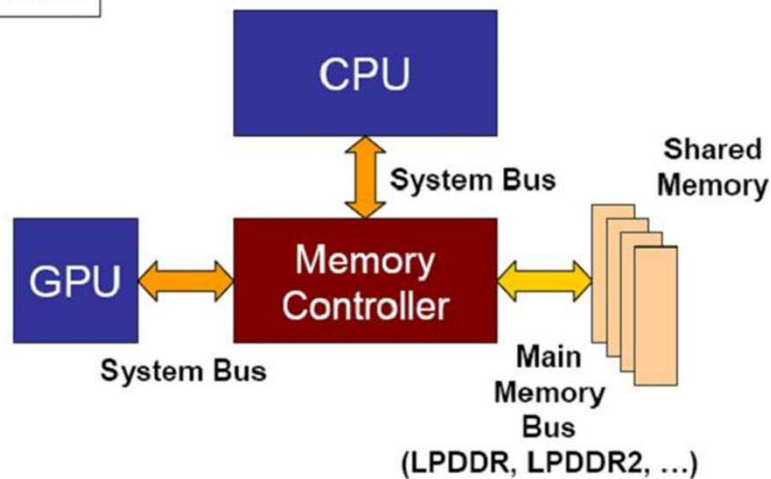
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The memory link bottleneck

Computing Scheme [Intel Journal Aug 2007]



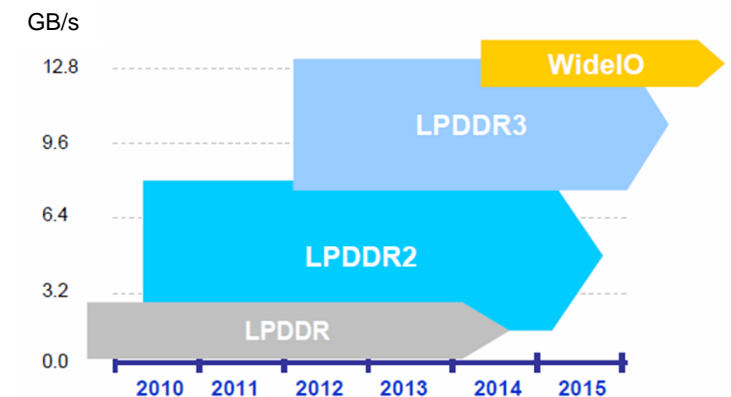
Mobile architecture



- The transfer Bandwidth between Memory and processor always been an issue for computing:
 - $BW = \text{nb of bits} \times \text{bit rate}$
- The needs of computing:
 - 2014: 1TB/s
- For Mobile Computing architecture is more constraining, both Graphic and system memory on same support
- The needs of Mobile computing:
 - 2010: 4GB/s
 - 2012: 12GB/s
 - 201X: 100GB/s




Standardization evolves to 3D stacked memory

- JEDEC JC-42.6 Subcommittee for Low Power Memories:
 - LPDDR2, LPDDR3, WideIO
- LPDDR2:
 - Advanced power management features
 - Shared interface for nonvolatile memory (NVM) and volatile memory (SDRAM)
- LPDDR3:
 - Extension of LPDDR2
 - Bandwidth reaching 6.4GBps and allowing 12.8GBps for a dual channel configuration.
 - Supports POP packaging type
- WideIO:
 - Breakthrough technology
 - Uses chip-level three dimensional (3D) stacking with TSV interconnects
 - Bandwidth is 12.8GBps



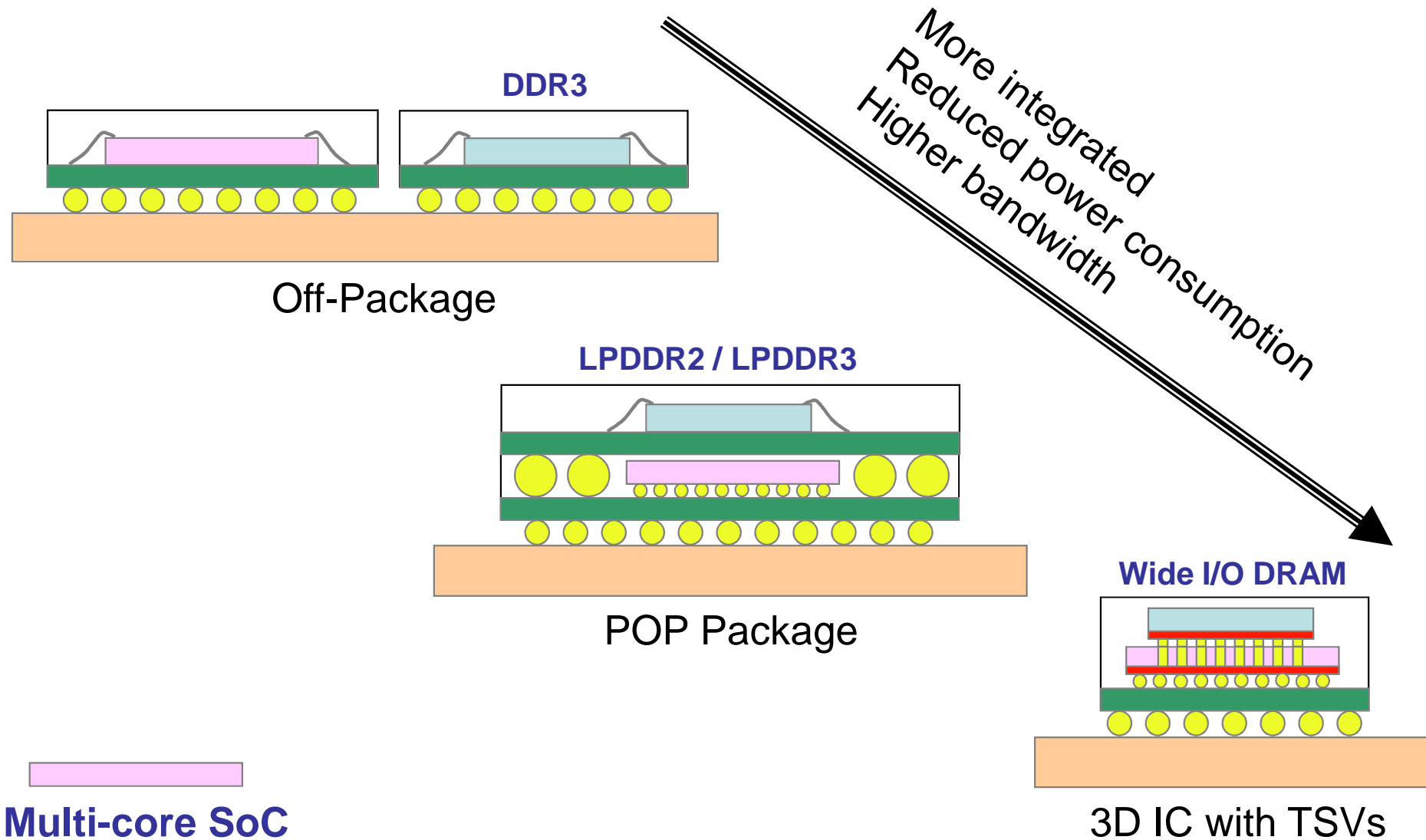
Information from JEDEC web site

IO and power cost for a 100GB/s memory bandwidth

Memory link, peak bandwidth and power consumption efficiency	Cost for 100 GB/s memory bandwidth	
	Number of data IO pins	Interface power consumption
 <p>533 MHz I/O bus clock, 32 bits, 1.2 V, Double Data Rate</p> <p>4.264 GB/s ~20 mW/Gb/s</p>	770	16 W
 <p>800 MHz I/O bus clock, 32 bits, 1.2V, Double Data Rate</p> <p>6.4 GB/s <20 mW/Gb/s</p>	770	<16 W
 <p>200 MHz I/O bus clock, 512 bits, 1.2 V, Single Data Rate</p> <p>12.8 GB/s 4 mW/Gb/s</p>	4100	3.2 W

- 3D integration of DRAM memory on processor with wide data interconnects provides higher data throughput and lower power consumption than 2D interfaces.

Memory-interface package evolution

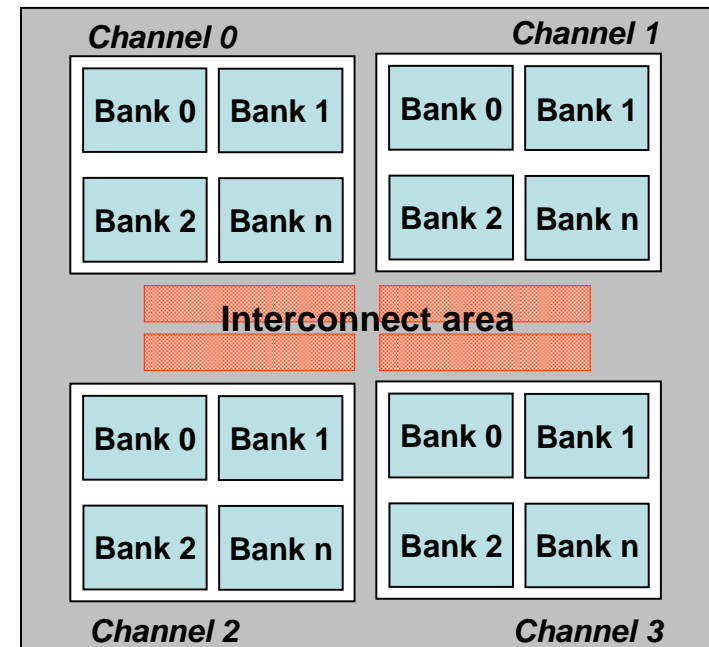


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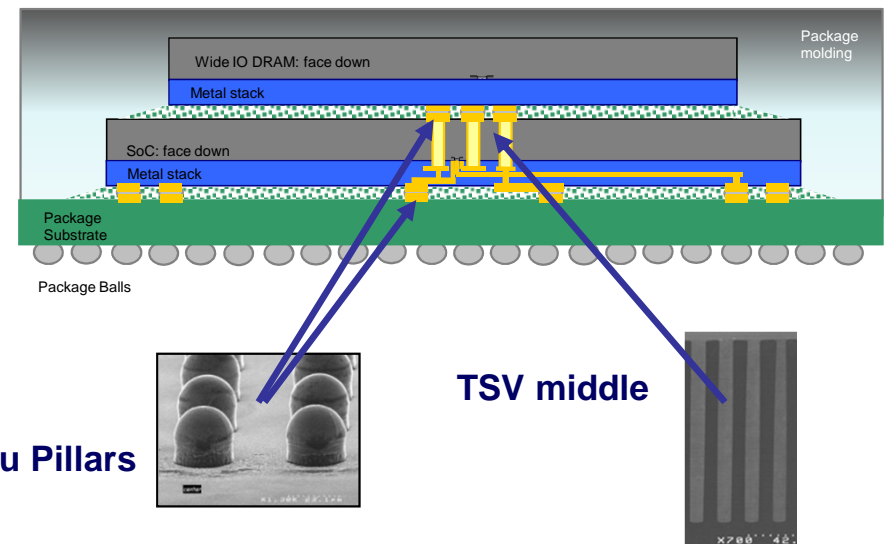
Wide IO technology

- Low power DRAM technology
- 12.8GByte/s peak bandwidth
- ~500mW power
- Quad-channel interface with large data bus operating at low frequency:
 - 128 bit wide data bus
 - Single Data Rate sampling mode @200MHz
 - Separate power-down & self-refresh per channel
- Timing performances:
 - Same as SDR 200MHz
- 1.2V low voltage supply
- Total I/O count including supply is in the range of ~1200:
 - IO physical location standardized at Jedec
 - 4 Arrays of 50x6; Pitch: 50μm x 40μm
 - Placed in the center area of the memory die
- Boundary scan test mode to detect bump connection failure between chips.
- Maximum number of stacked dies is 4



Wide IO DRAM floorplan

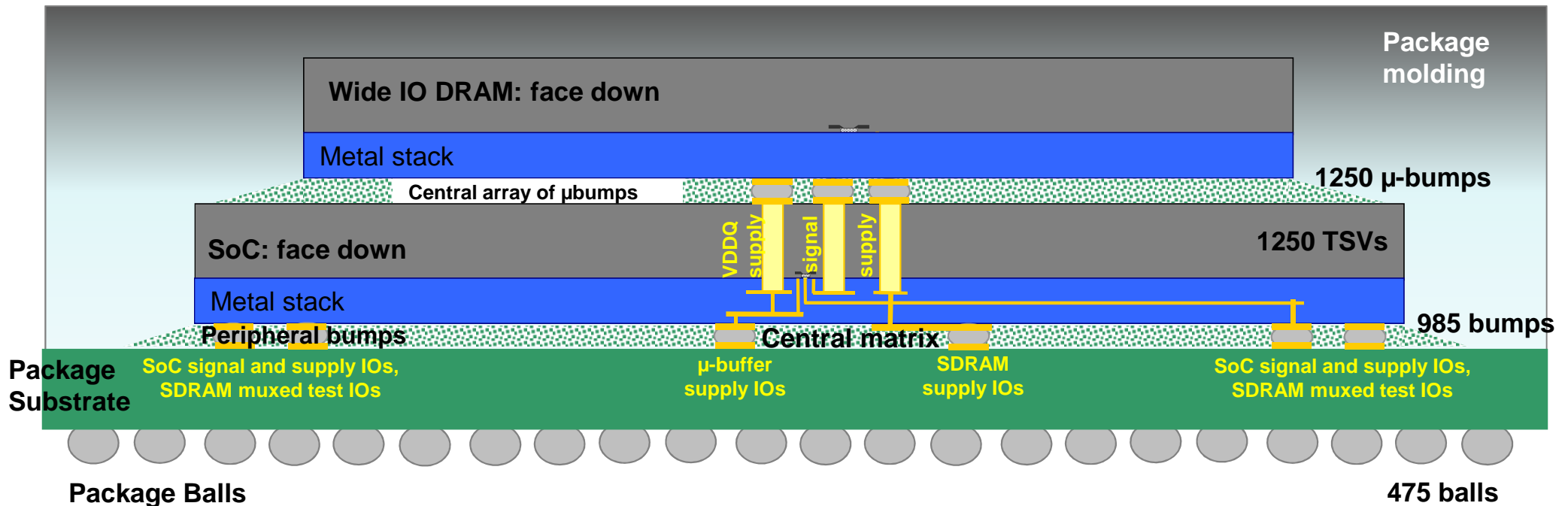
3D-IC with Wide IO DRAM



Mag3D test chip program

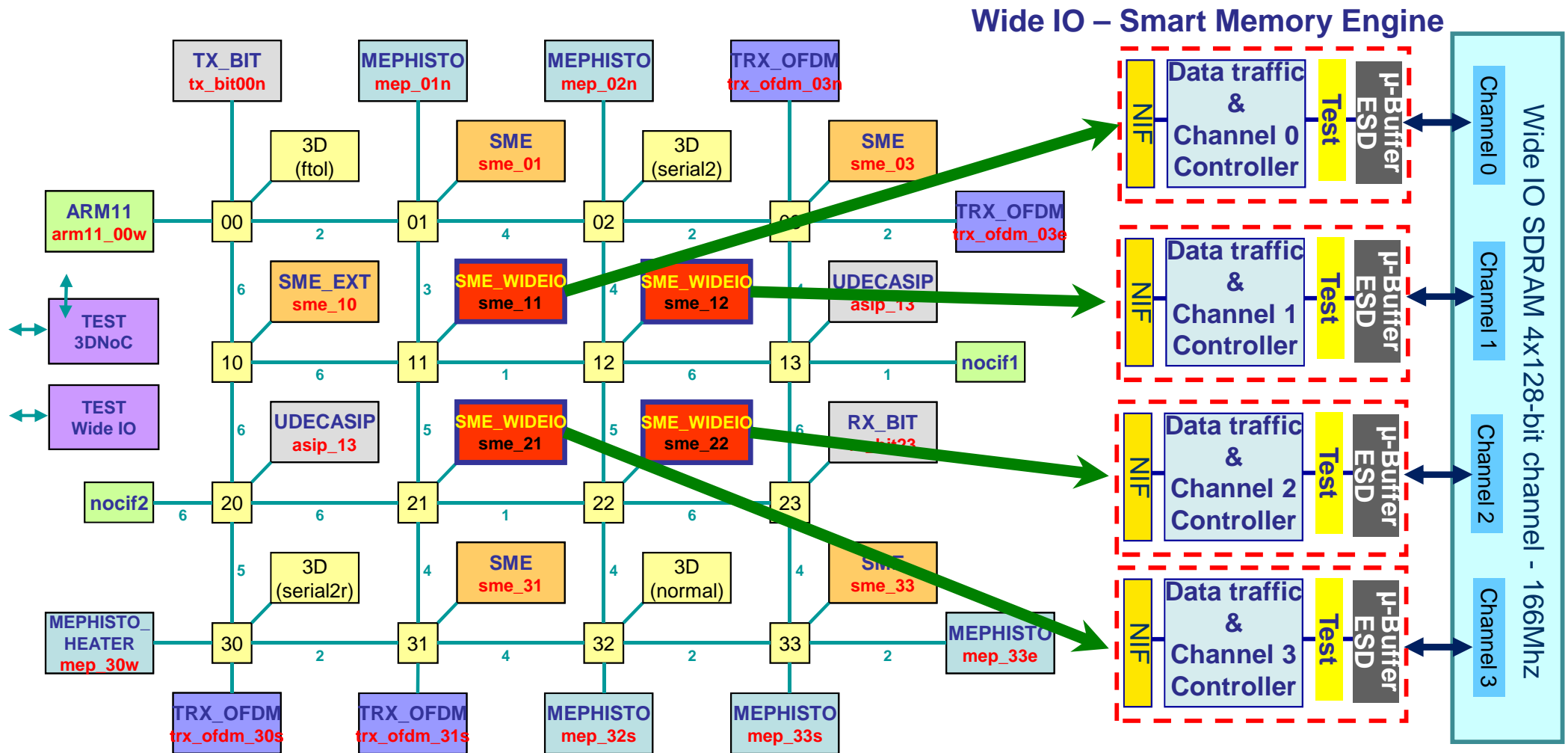
- Partnership between LETI, STEricsson, STMicroelectronics and Cadence
- Wide IO DRAM die is stacked on top of the SoC (Mag3D) in the same package
- Face to Back stacking
- Memory supplies and interconnect signals go through the SoC by means of TSVs

Technology assumptions	
Assembly	D2D
Stacking	F2B
TSV process	Via Middle
TSV density	10 μ m diameter
TSV xy pitch	50 μ m x 40 μ m
Copper Pillars	25 μ m diameter

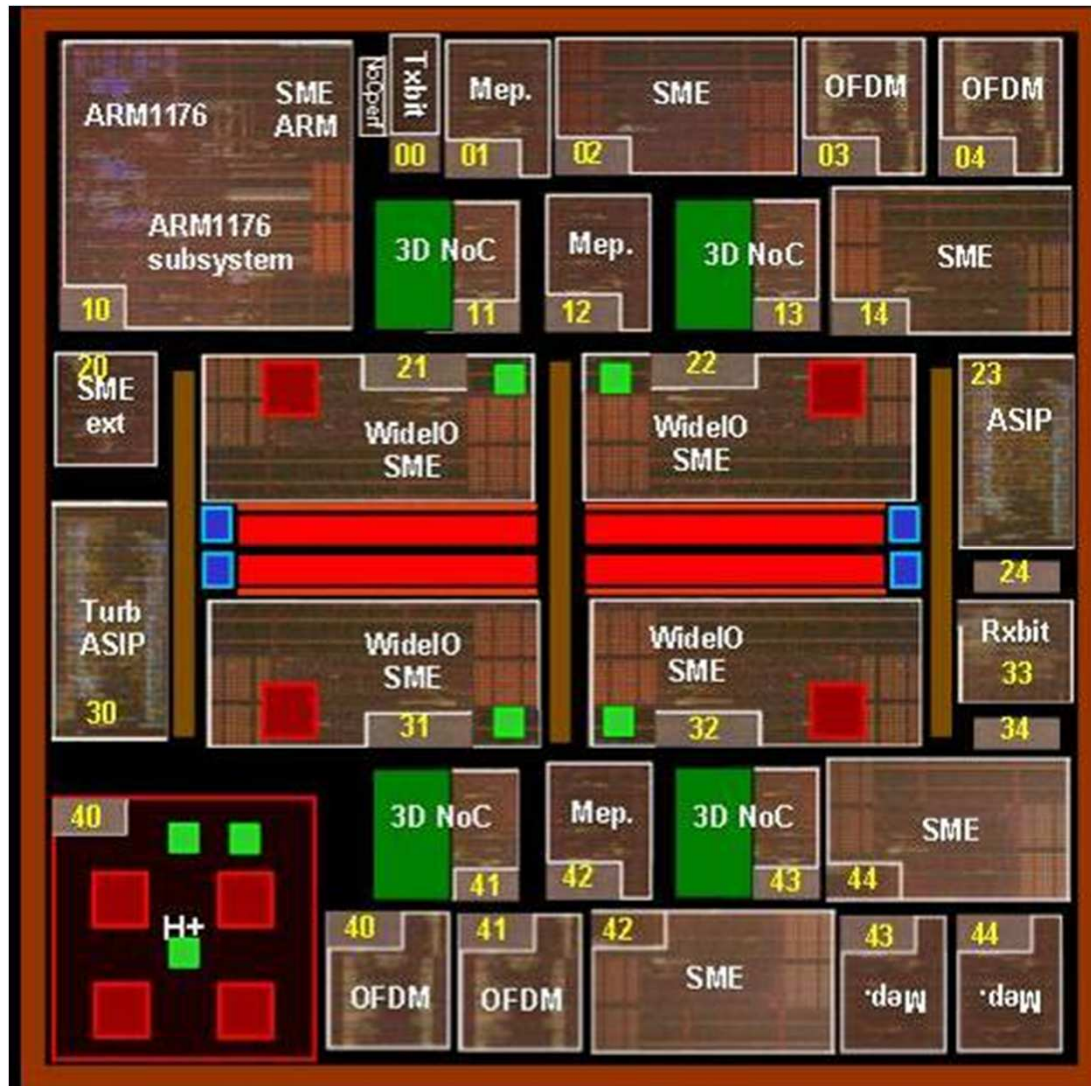


Wide IO integration into Mag3D

- 3D test chip baseline is the 65nm LETI MAGALI SoC
- The NoC architecture has been extended to support Wide IO memory
- Four independent data traffic and memory controllers have been added



Mag3D topology & floorplan

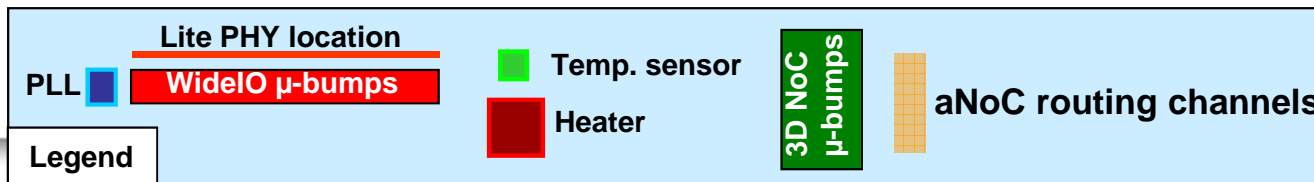


MAG3D few numbers :

- CMOS 65nm + TSV middle $\varnothing 10\mu\text{m}$
- 8500 μm x 8500 μm (72mm²)
- 1.8 M-instances
- 400 Macros
- 270 IO pads
- 985 Bumps (Flip-Chip)
- 1980 TSV for 3D NoC
- 1250 TSV for WideIO memory

Performances :

- Units in the [350 - 400] MHz range
- Asynchronous NoC \sim 550 MHz
- Overall power : 500mW – 1W



Physical implementation challenges with 3D design

- Supply distribution for Wide IO memory and micro-buffers
- 3D interconnect routing: flip chip bumps, RDL, TSV and backside micro-bumps
- ESD strategy
- Test constraint integration
- Final verification (LVS for 3D stack)

Conclusion & Perspectives

- TSV technology is mature enough to allow coarse grain partitioning with ~ 500 TSV per mm^2
 - In mobile computing, off-package memory interfaces have reached their limit above ~ 10 GByte/s:
 - In the coming years, multi-core processor will require more than 100GB/s for a reasonable power budget
 - 3D stacking technology enables a power efficiency breakthrough in memory interconnect
 - Progress to be done with 3D design flow
- Be ready to integrate 3D in your current architecture hypothesis

Many Thanks ...

- To our partners in this project
 - STMicroelectronics, ST-Ericsson, CADENCE



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